

“Sensor Prototypes for CEPC Vertex Detector”



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on behalf of CEPC pixel sensor development teams

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Outline

- Introduction
 - General requirement for the CEPC vertex detector
- Pixel prototype
 - Sensor prototypes
 - Test results of “Jadepix1”
 - MOST2 pixel project
- Summary

Main Beam Parameter for CEPC operation

	Higgs	W	Z (3T)	Z (2T)
Center-of-mass energy (GeV)	240	160	91	
Number of IPs	2			
Luminosity/IP ($10^{34} \text{ cm}^{-2} \text{ s}^{-1}$)	3	10	16	32
Number of years	7	1	2	
Total Integrated Luminosity (ab^{-1}) - 2 IP	5.6	2.6	8	16
Total number of particles	1×10^6	2×10^7	3×10^{11}	7×10^{11}
Bunch numbers (Bunch spacing)	242 (680 ns)	1524 (210 ns)	12000 (25ns + 10% gap)	

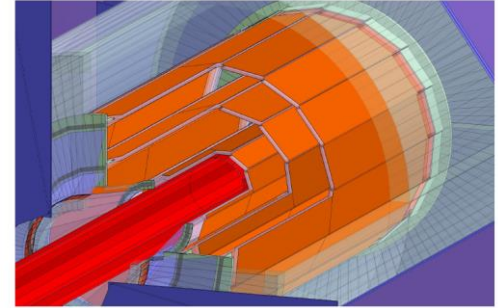
- Continuous colliding mode
 - Duty cycle ~ 50% @ Higgs, close to 100% @ W/Z
- General requirement on the detector development:
 - Precise measurement, Low power, Fast readout, Radiation-hard

from CDR

Baseline Silicon Tracker Layout

- Tracker

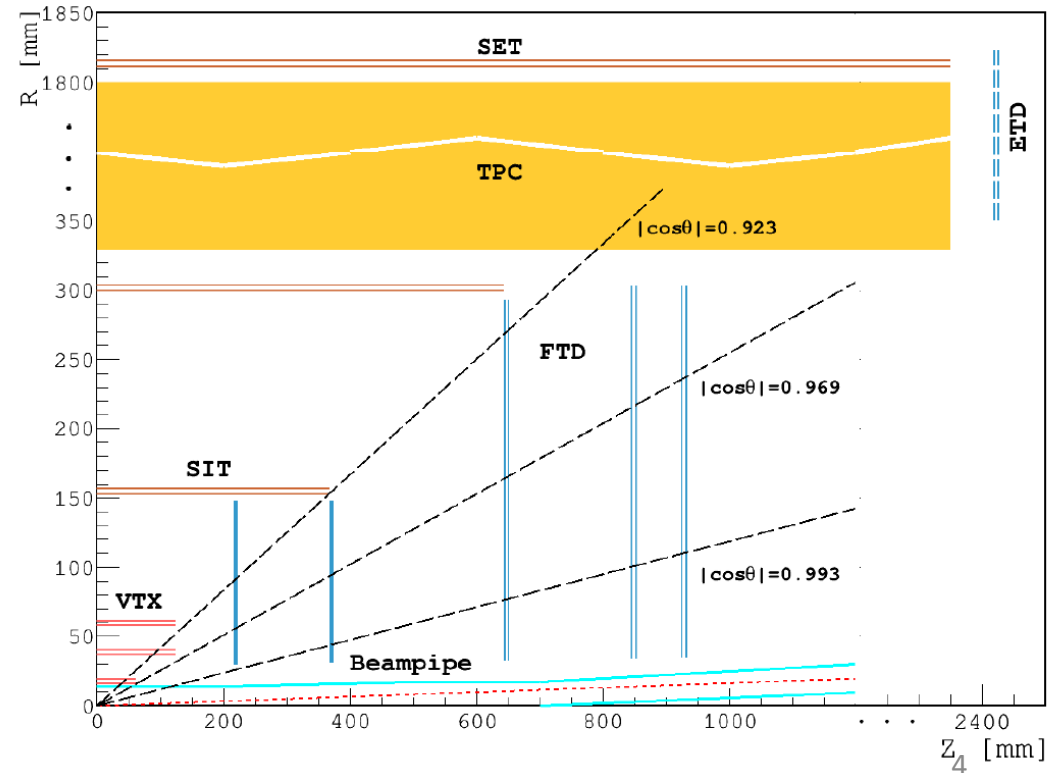
- SIT, SET, ETD, and 3 outer disks of FTD, ETD: single-sided strips mounted back to back
- 2 inner disks of FTD: pixel



- Vertex detector

- 3 double-sided pixel layers

	R (mm)	$ z $ (mm)	$ \cos \theta $	σ (μm)
Layer 1	16	62.5	0.97	2.8
Layer 2	18	62.5	0.96	6
Layer 3	37	125.0	0.96	4
Layer 4	39	125.0	0.95	4
Layer 5	58	125.0	0.91	4
Layer 6	60	125.0	0.90	4



Performance Requirements

$B = 3T$

- Momentum Resolution: $\sigma_{1/p_T} = 2 \times 10^{-5} \oplus 1 \times 10^{-3} / (p_T \sin \theta)$
- Impact Parameter Resolution: $\sigma_{r\phi} = 5 \mu m \oplus \frac{10}{p(\text{GeV}) \sin^{3/2} \theta} \mu m$

■ Vertex specifications:

- σ_{SP} near the IP: $\leq 3 \mu m$
- Material budget: $\leq 0.15\% X_0 / \text{layer}$
- First layer located at a radius: $\sim 1.6 \text{ cm}$
- Pixel occupancy: $\leq 1 \%$

■ Tracking specifications:

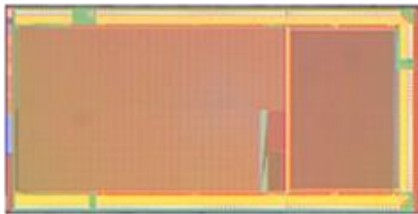
- $\sigma_{SP} : \leq 7 \mu m$
- Material budget: $\leq 0.65\% X_0 / \text{layer}$

Pixel Sensor Specification

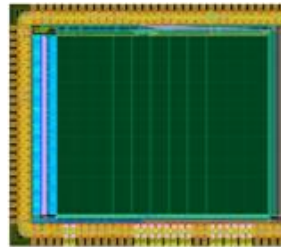
- To achieve single point resolution
 - Pixel size $\sim 16 \mu\text{m}$ (Binary readout)
- To lower the material budget
 - Sensor thickness $\sim 50 \mu\text{m}$
 - Air cooling, heat load $< 50 \text{ mW} / \text{cm}^2$
- To tackle beam-related background
 - Fast readout $1 \sim 100 \mu\text{s} / \text{frame}$
 - $3.4 \text{ Mrad} / \text{year}$ & $6.2 \times 10^{12} n_{\text{eq}} / (\text{cm}^2 \cdot \text{year})?$

Pixel Sensor Prototypes

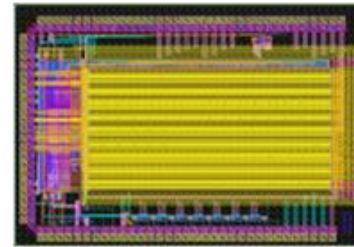
	Process	Pixel Pitch (μm^2)	Matrix size	R/O architecture
"JadePix1"	CMOS	33x33/16x16	96x160/192x128	Rolling Shutter
"JadePix2"	CMOS	22x22	128x64	Rolling Shutter
"MIC4"	CMOS	25x25	112x96	Asynchronous
"CPV2"	SOI	16x16	64x64	Rolling Shutter



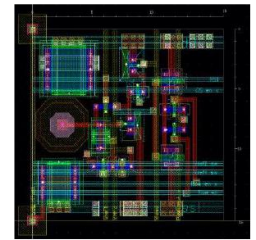
JadePix1
(3.9 x 7.9 mm²)



JadePix2
(3 x 3.3 mm²)



MIC4
(3.2 x 3.7 mm²)



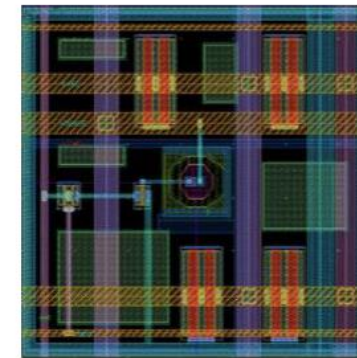
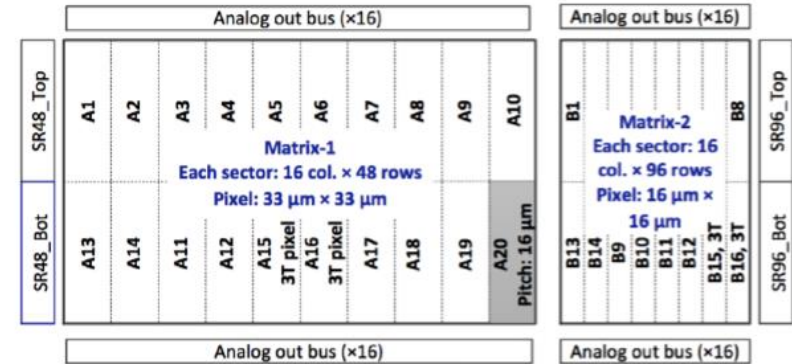
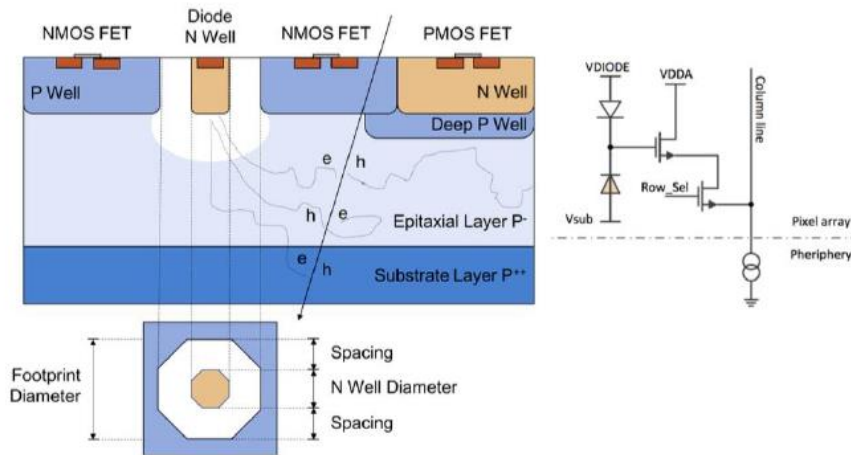
CPV2

Detail will be presented by
Dr. Yang Zhou (next talk)

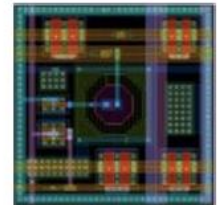
Hereafter, introduce JadePix1

Prototype CMOS Pixel Sensor : JadePix1

- TJ 0.18 μm CMOS image process with high resistance epi-layer
- Goal: sensor diode **geometry optimization**
- Design remarks:
 - **diode area, footprint**
 - **pixel pitch**



33 x 33 μm^2

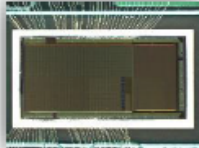





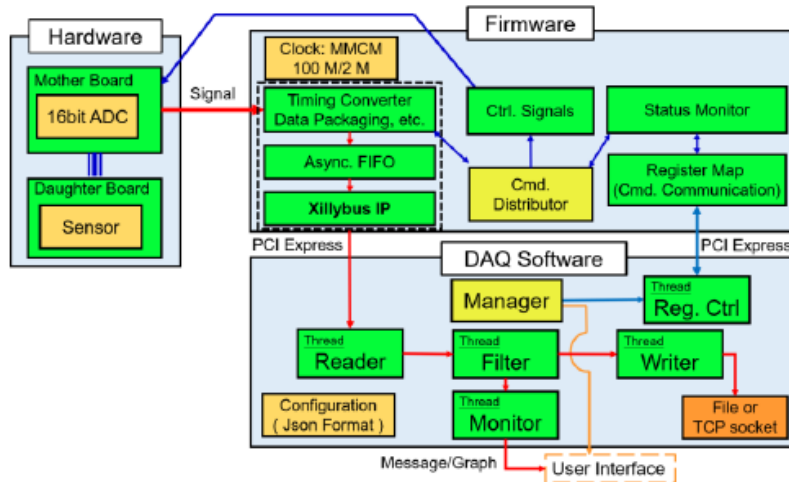
16 x 16 μm^2

- Submission in Nov 2015, test system developed and validated in 2017, detailed performance characterization this year

DAQ System

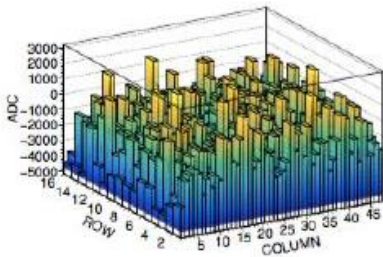
- Analog signal from sensor amplified on the daughter board
- Converted to digital signal on the mother board
- Data transmitted to PC via PCIe after processed on evaluation board
- Data took automatically with modern multi-thread C++ software

			
JadePix-1: TJ 180 nm CPS	Daughter Board: 16 channels amplifier	Mother Board: 16 bit ADC	KC705 FPGA Board: 6 Gbps PCIe

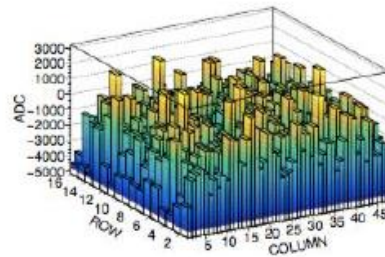


Test with ^{55}Fe

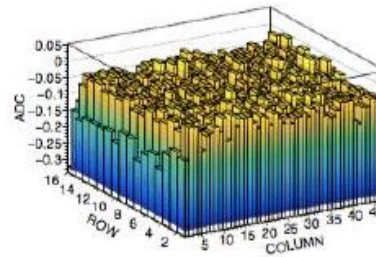
- Correlated Double Sampling (CDS) to suppress noise and extract signals
- Noise measured with/without radioactive source (exclude suspected signals and get multiple frames average)



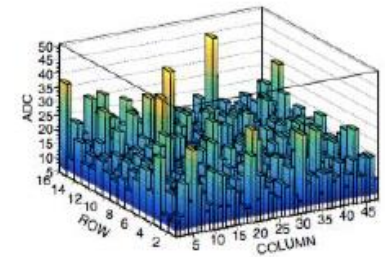
(a) First frame raw data



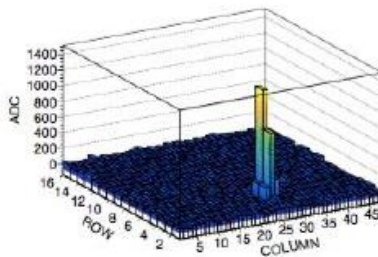
(b) Second frame raw data



(a) Pedestal distribution for 1 frame



(b) Noise distribution for 1 frame



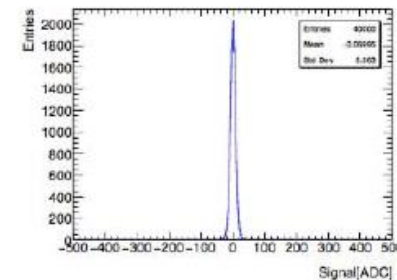
(c) CDS

$$r_k^i = s_k^i + p_k^i + c^i$$

$$p_{k,N} = \frac{1}{N} \sum_{i=1}^N (r_k^i - s_k^i) = \frac{1}{N} \sum_{i=1}^N \tilde{r}_k^i$$

$$p_{k,N}^{\text{est}} = \frac{1}{N'} \sum_{j=1}^{N'} \tilde{r}_k^j$$

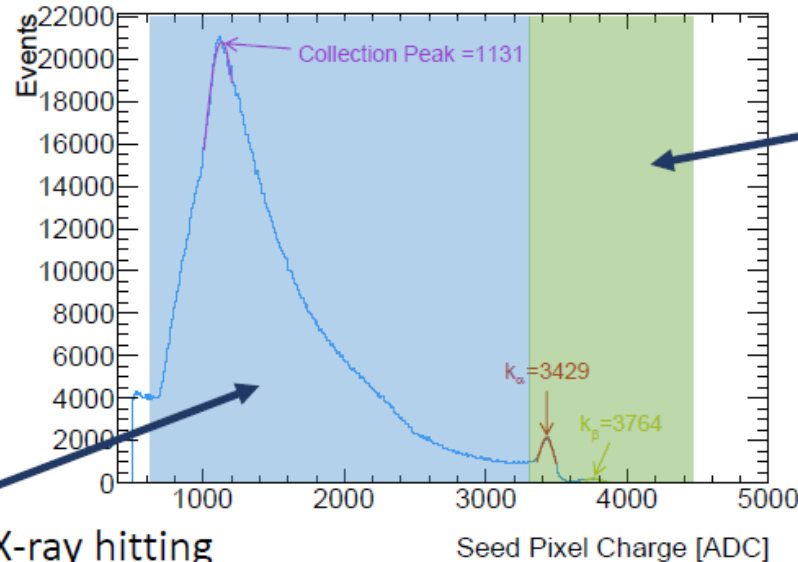
$$n_{k,N} = \sqrt{\frac{N'}{N'-1} \left[\left(\frac{1}{N'} \sum_{j=1}^{N'} (\tilde{r}_k^j)^2 \right) - (p_{k,N}^{\text{est}})^2 \right]}$$



(c) CDS signal for 1 pixel

^{55}Fe Calibration

- ^{55}Fe used to calibrate the pixel gain on the assumptions:



the charges with X-ray hitting on diode is complete conversion

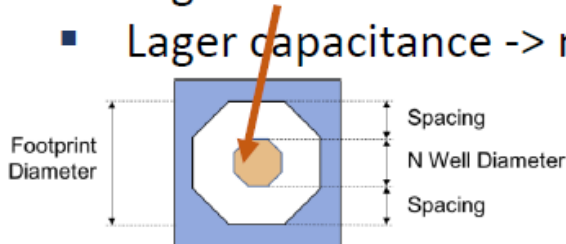
the charges with X-ray hitting other place disperse slowly towards diode on thermal diffuse to neighbor pixel

- ^{55}Fe generate two low energy X-ray:
 - 5.9 keV (90%)
 - 6.49 keV (10%)
- 5.9 keV X-ray produced electron-hole pairs:

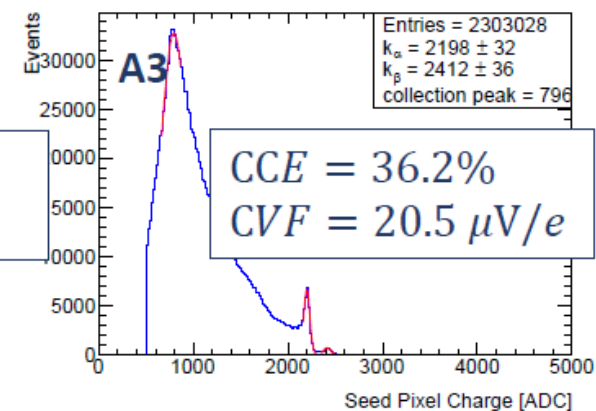
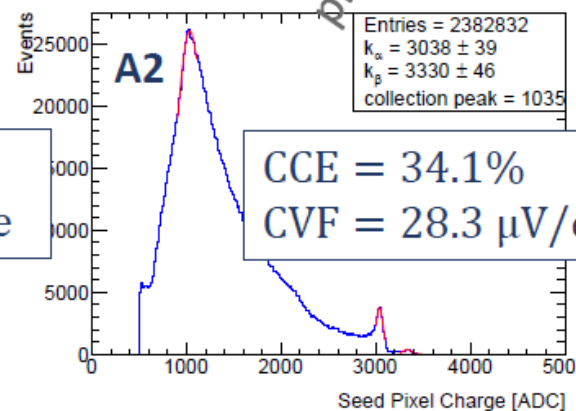
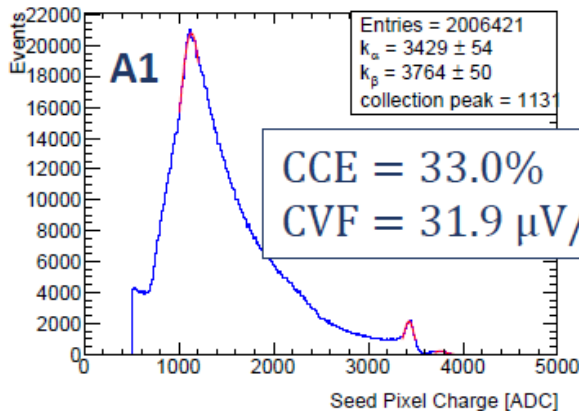
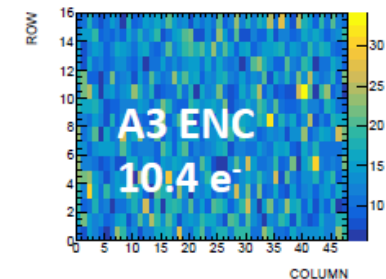
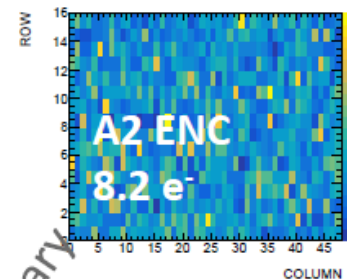
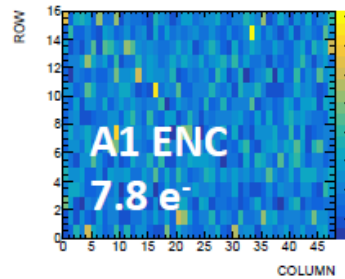
$$N_{e-h} = \frac{E_{\alpha}}{\varpi} = 1640$$

Diode Surface

- Larger diode surface -> more effective charge collection
- Larger capacitance -> more sensor noise



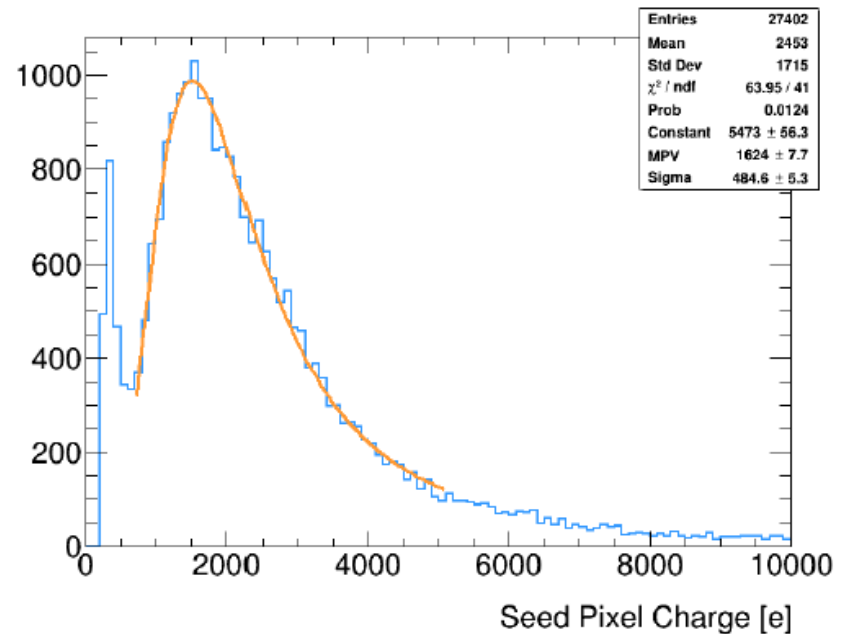
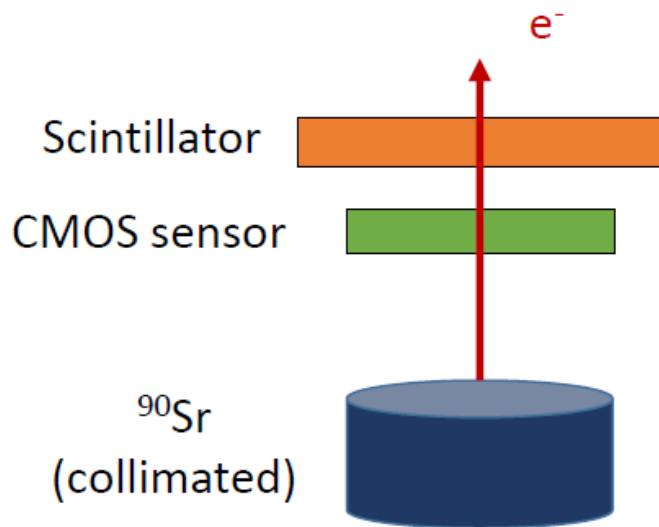
Sector	Diode surface	Footprint
A1	4 μm^2	30 μm^2
A2	8 μm^2	30 μm^2
A3	15 μm^2	30 μm^2



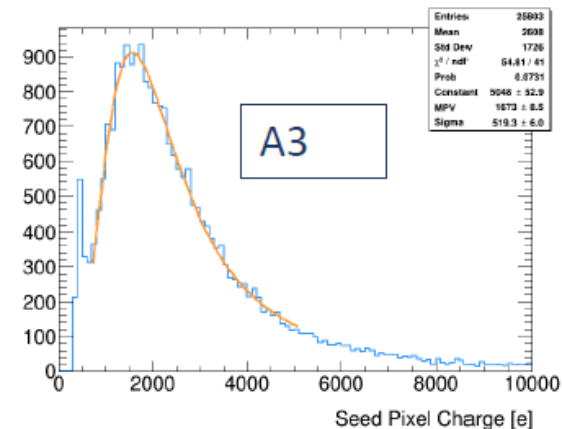
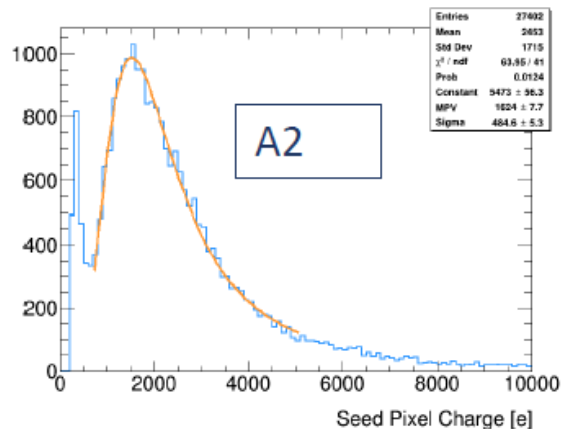
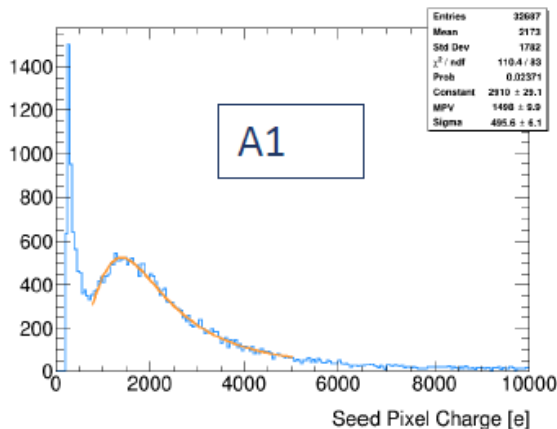
preliminary

Test with ^{90}Sr

- Scintillator+ SiPM to provide the trigger signal
- Charged collected by the seed pixel estimated as the most probable value derived from the Landau function fit to the charge distribution



Charge Collection

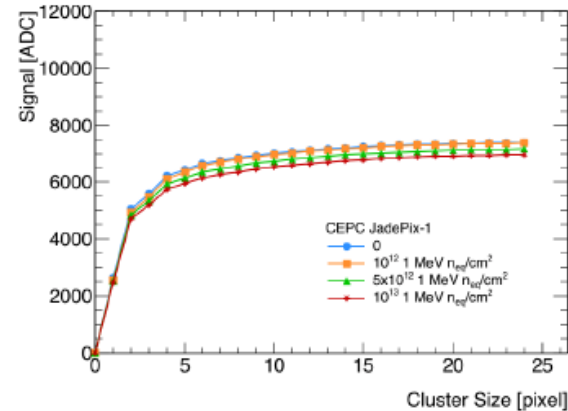
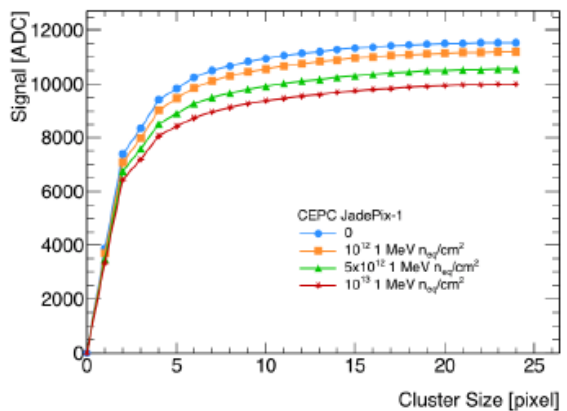
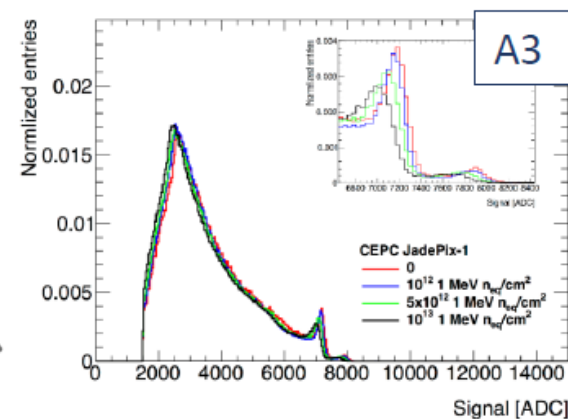
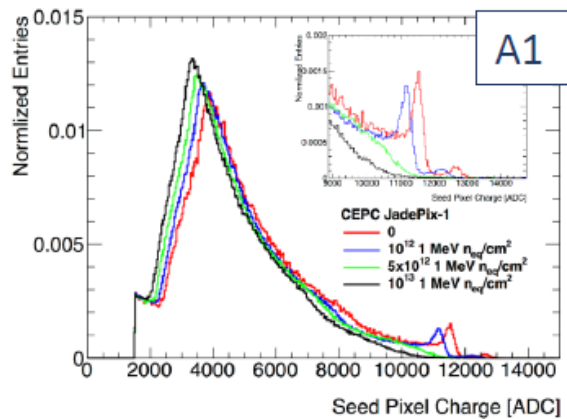


preliminary

Sector	Seed Charge [e-]	Cluster Charge [e-]	CCE	S/N
A1	1498	3893	38.48%	237
A2	1624	3973	40.87%	229
A3	1673	3784	44.22%	180
A4	1391	3822	36.39%	234
A7	1361	3985	34.15%	220

Performance After Irradiation

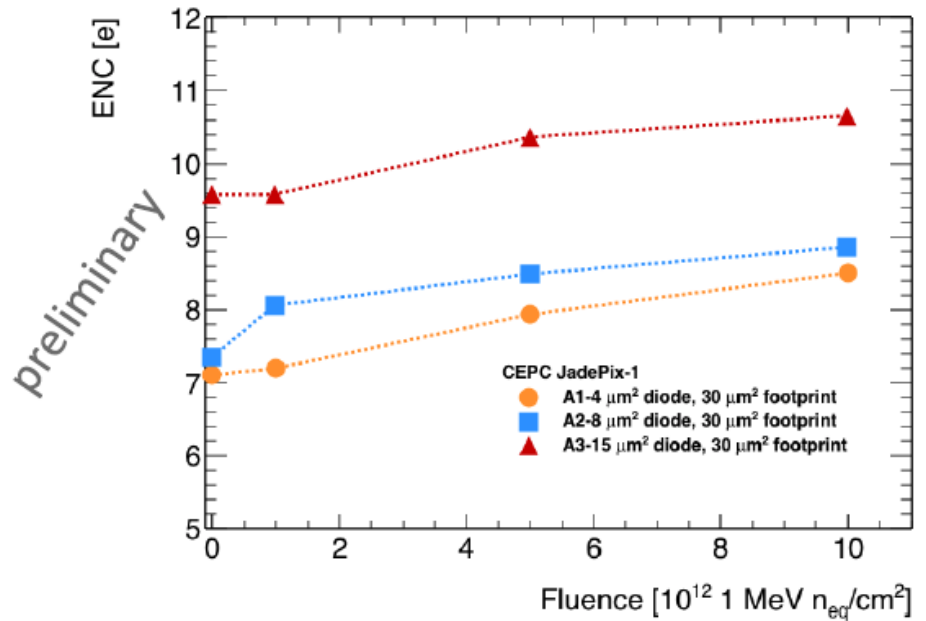
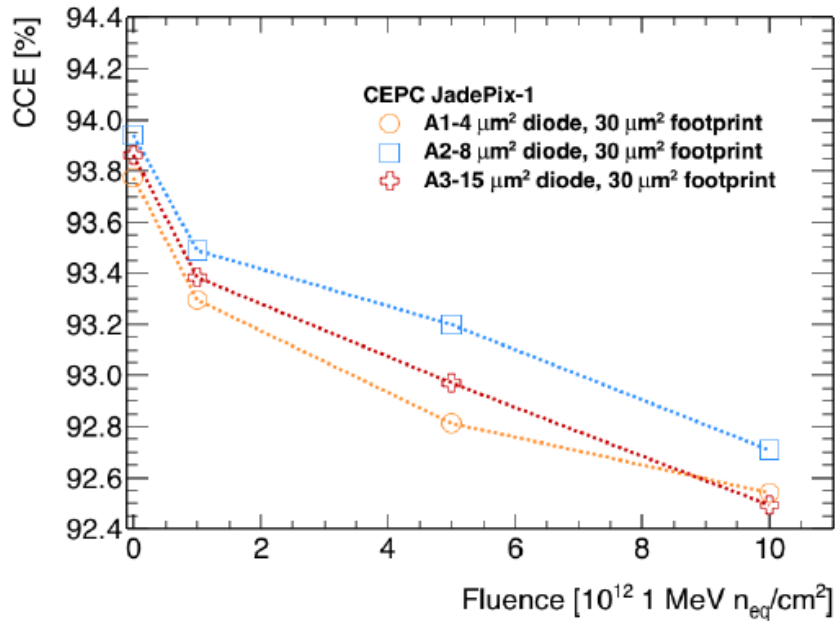
- Samples sent to a pulsed neutron reactors and irradiated to fluences of 10^{12} , 5×10^{12} , and 10^{13} $1 \text{ MeV } n_{\text{eq}}/\text{cm}^2$
- Larger diode (A3 > A1) more radiation hard as expected



preliminary

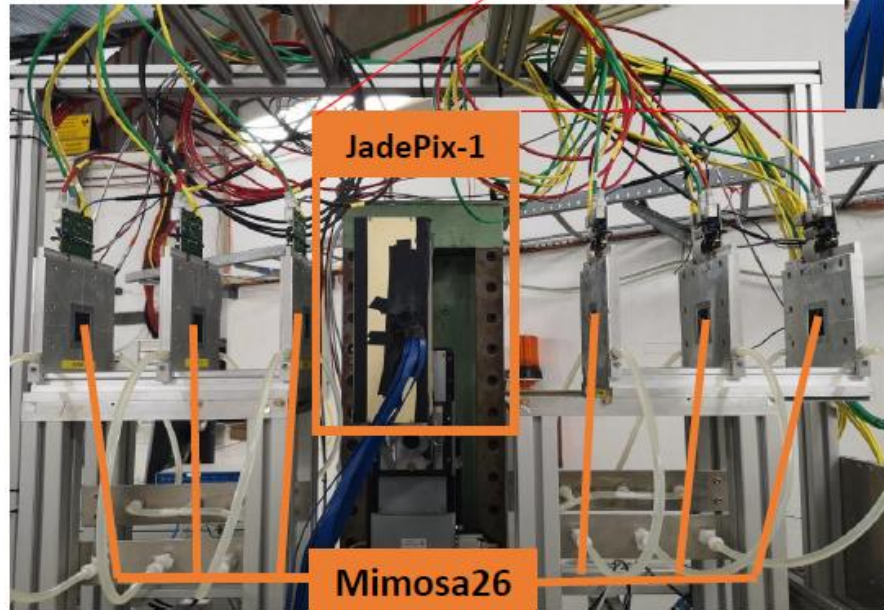
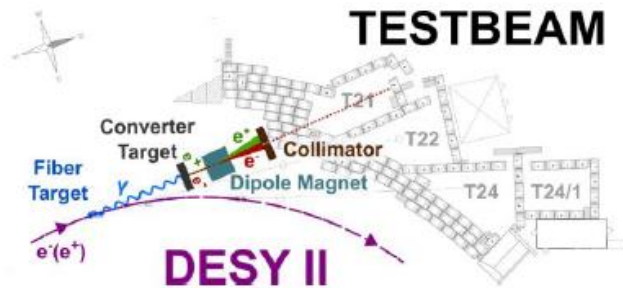
Performance After Irradiation

- Charge collection efficiency decreases but noise increases as the neutron fluence goes higher



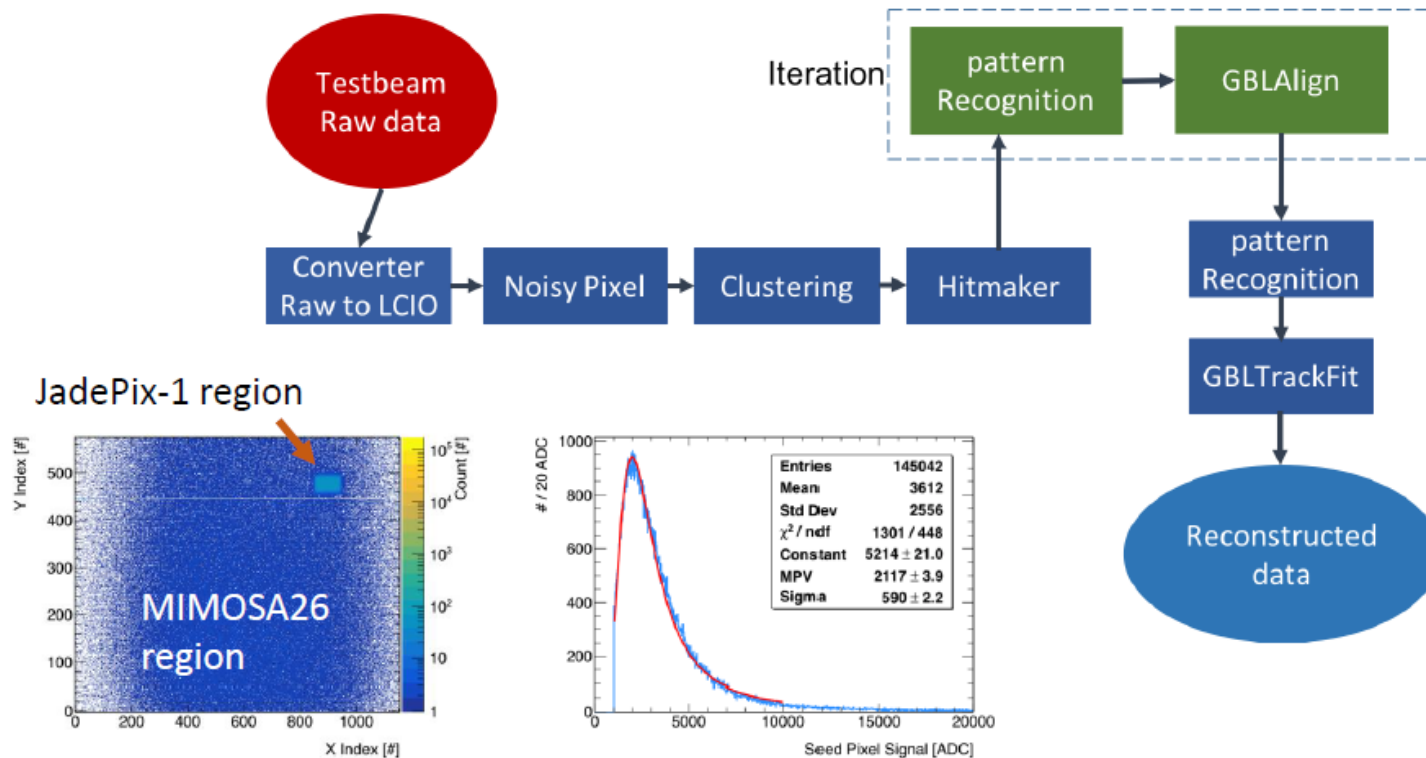
Tests with Electron Beams

- Sensor characterized with the DESY electron beam in September
 - Beam energy 1-6 GeV, beam size $1 \times 1 \text{ cm}^2$, data taken at 4.4 GeV
 - EUDET beam telescope, spatial resolution $2 \sim 3 \mu\text{m}$ at DUT



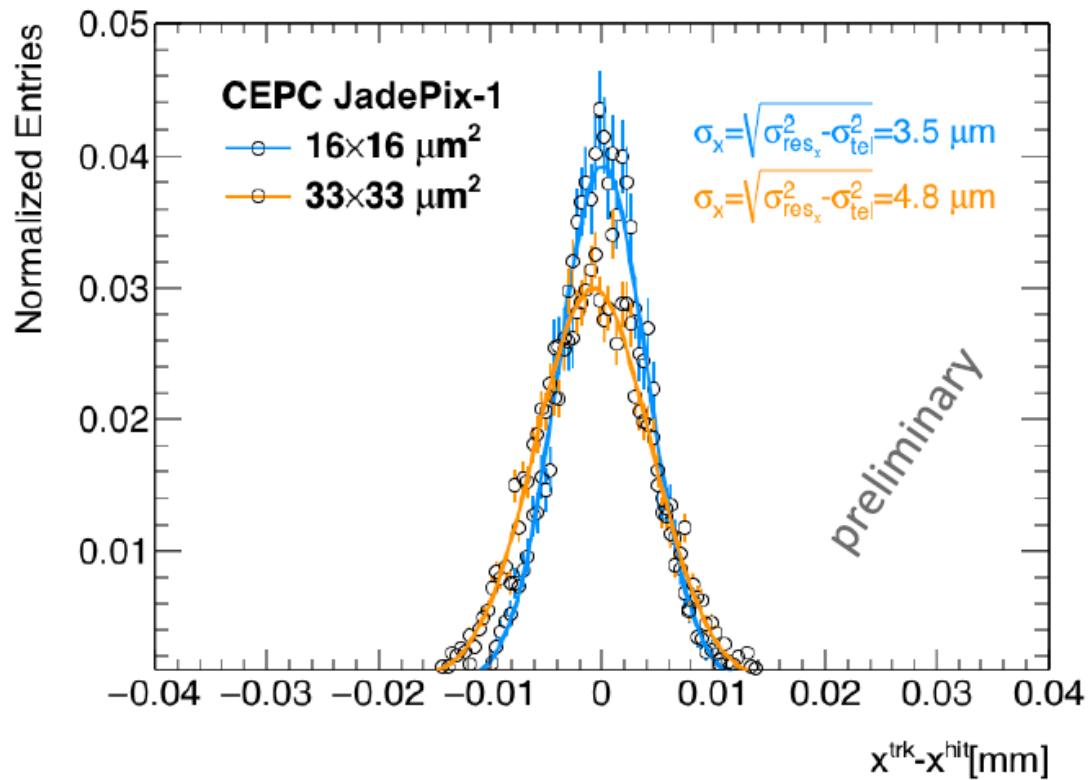
Track Reconstruction

- Raw data converted to LCIO format using a customized EUDAQ version
- Sparse clustering to group pixels if they are within the defined distance
- General Broken Lines (GBL) algorithm to align reference planes and DUT



Spatial Resolutions

- Spatial resolutions better than 5 μm and 3.5 μm achieved for pixel sizes of 33x33 μm^2 and 16x16 μm^2

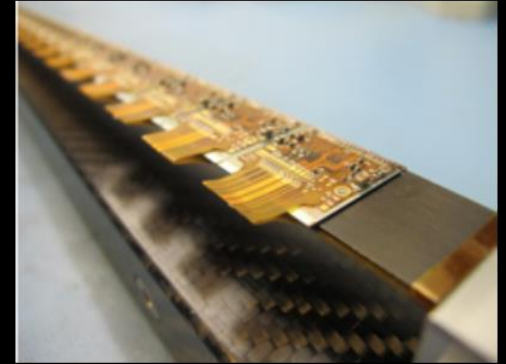


MOST2 -- Pixel Detector Project

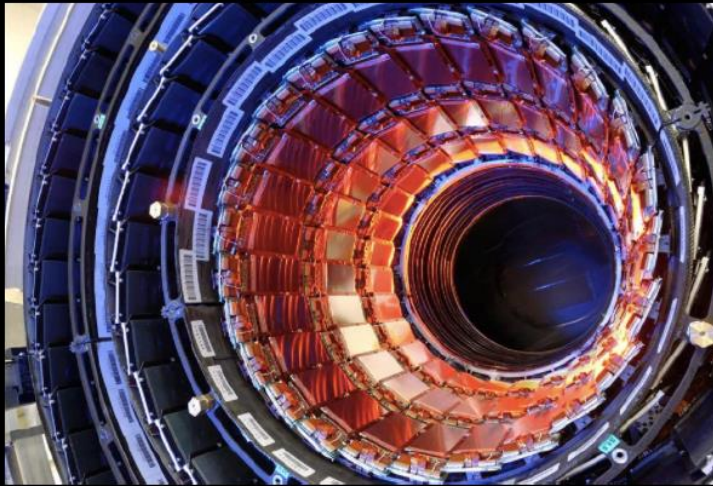
Task 2: Research Goal

- **Produce a world class vertex detector prototype**
 - Spatial resolution 3~5 μm (pixel detector)
 - Radiation hard (>1 MRad)
- **Preliminary design of prototype**
 - Three layer, module $\sim 1\text{ cm} \times 6\text{--}12\text{ cm}^2$

Typical module



Typical tracker

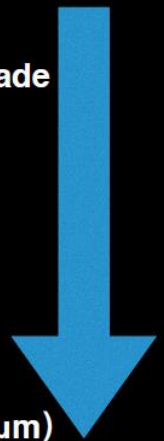


Resolution

ATLAS/CMS upgrade
(15 μm)

Alice upgrade
(8~10 μm)

World leading This project (3~5 μm)



- Ref: Introduction to the Pixel MOST2 Project, Joao Costa, 2018.6

MOST2 -- Pixel Detector Project

Task 2: Technical route and schedule

Use CMOS image sensor technology

Optimize pixel circuitry, reduce size

Special design and latest technology

High resolution

Radiation hard

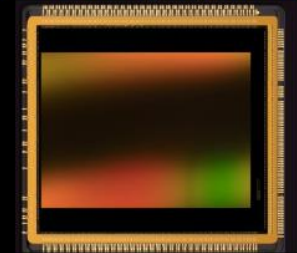
Use carbon fiber, polyamide, graphene, and other light materials for mechanical structure

Low mass

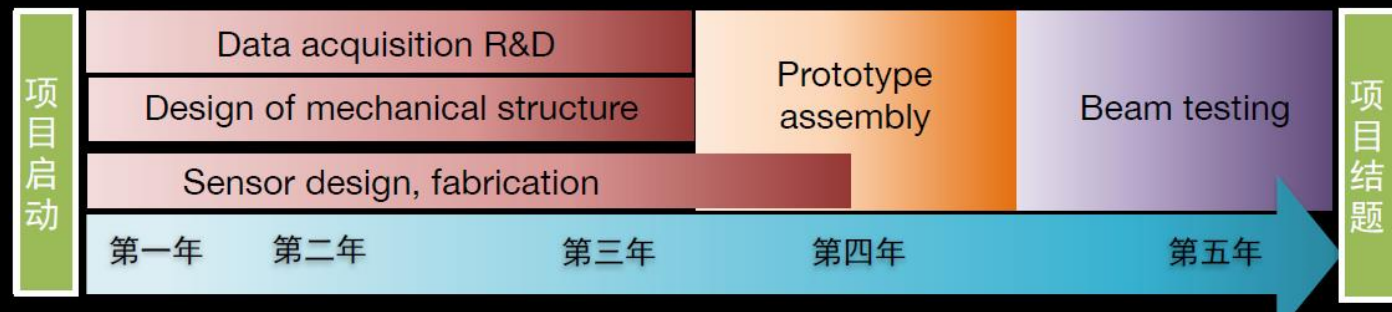
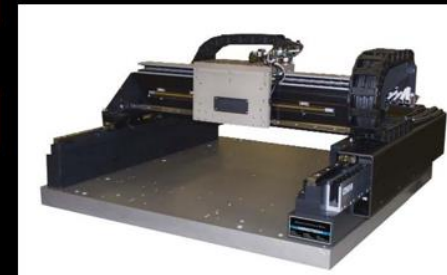
Robot automatic mechanical assembly

High accuracy

CMOS imaging sensor



Gantry



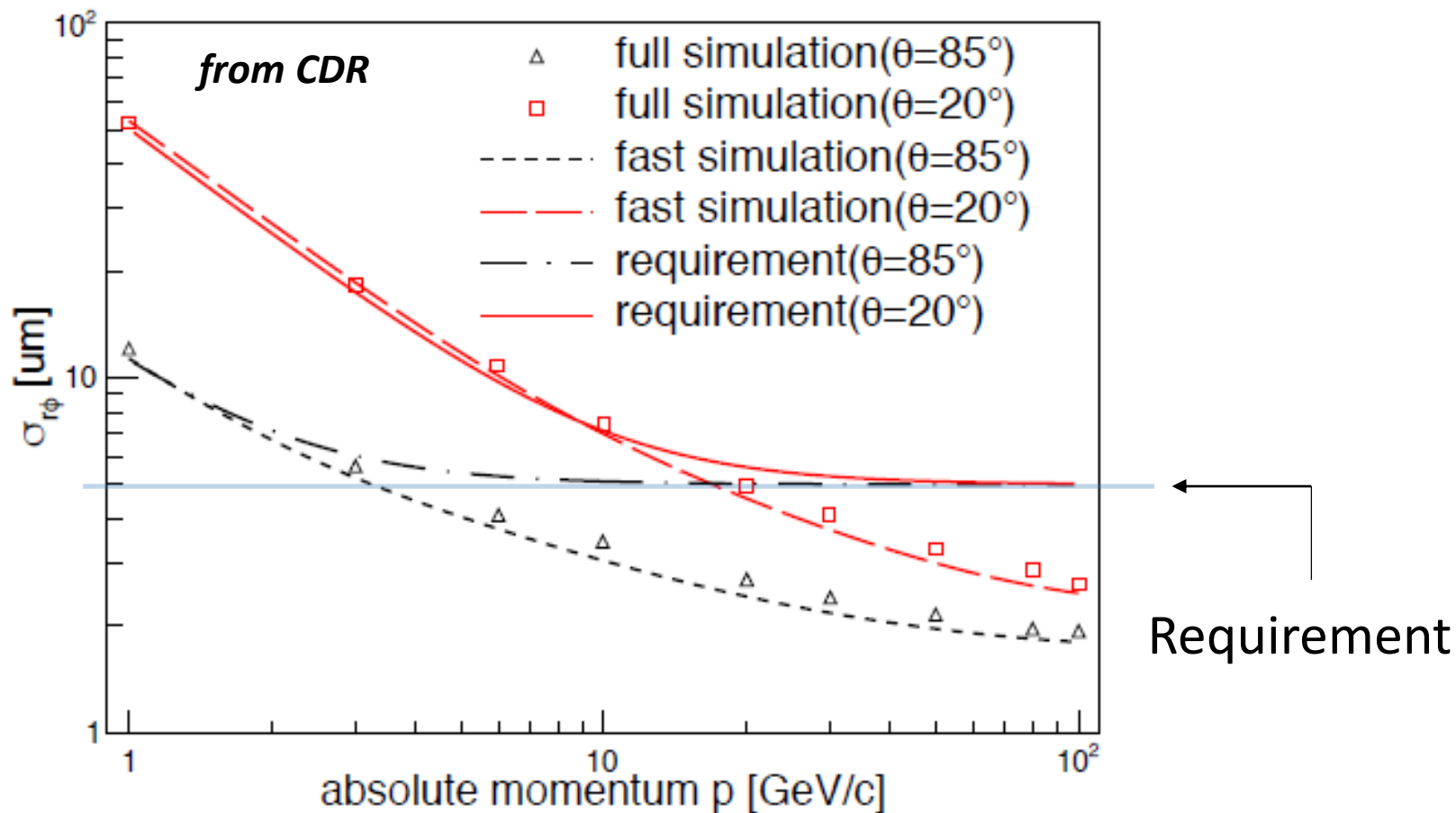
- Ref: Introduction to the Pixel MOST2 Project, Joao Costa, 2018.6

Summary

- Pixel design of high spatial resolution, low power and fast readout is required for the CEPC silicon tracker.
- Several types of prototype pixel sensors for the CEPC are designed. Characterization of the prototype, JadePix1, discussed in this talk as one of example, gives us useful information for future designs.
- All those R&D, including the MOST2 project, are now on-going.

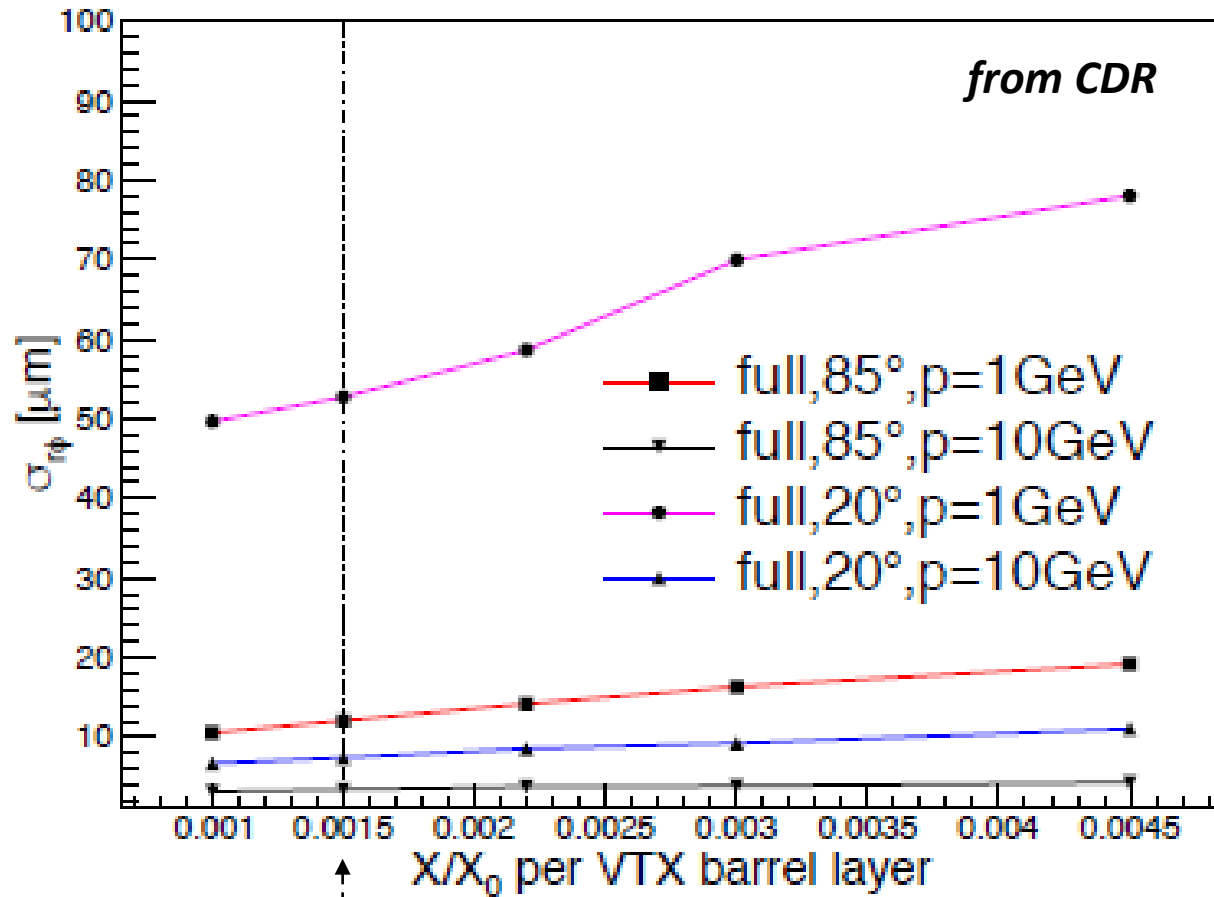
Backup

Performance studies: Impact parameter resolution



Impact parameter resolution goal achievable with current design

Performance studies: Material budget



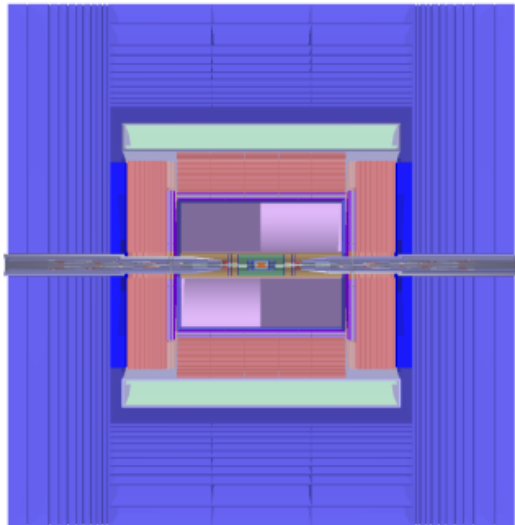
It is studied that the resolution degrades by $\sim 20\%$, when increasing the material of all detector layers by a factor of two

Requirement

Two Detector Concepts

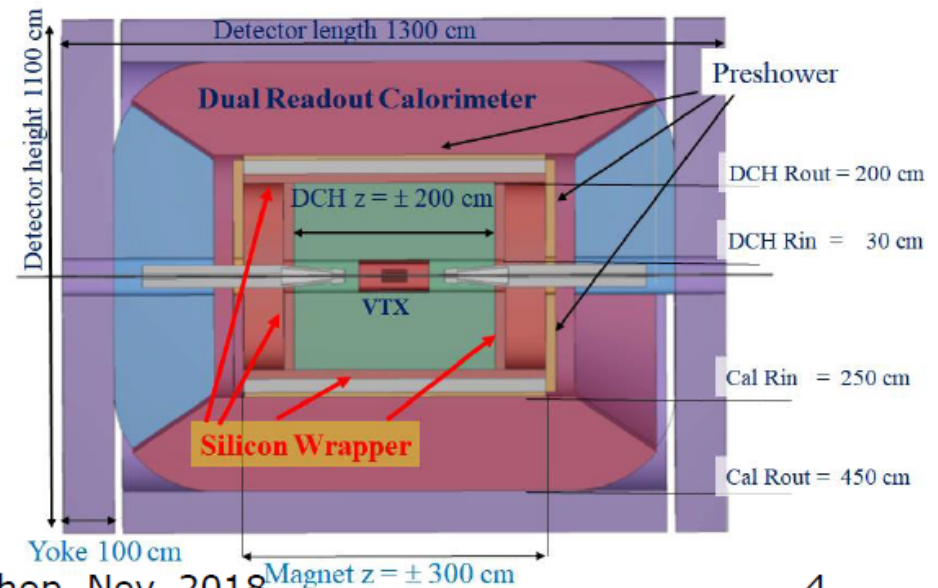
■ Baseline detector concept

- Silicon tracker + TPC or Full Silicon Tracker
- High granular calorimetry system
- 3 Tesla solenoid
- Muon detector



■ Alternative detector concept, IDEA

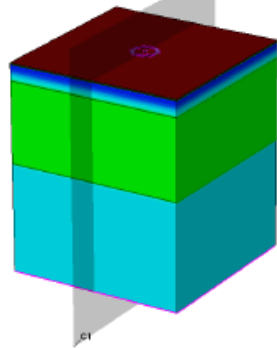
- Silicon pixel + Drift Chamber
- 2 Tesla solenoid
- Dual readout calorimeter
- Muon chamber



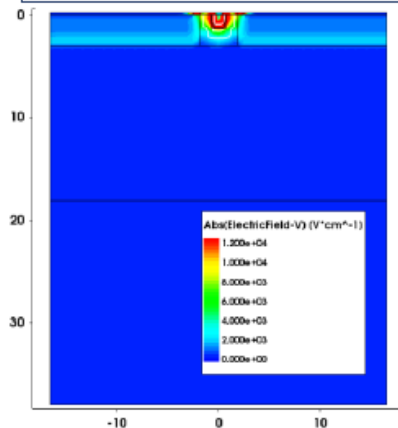
Simulation



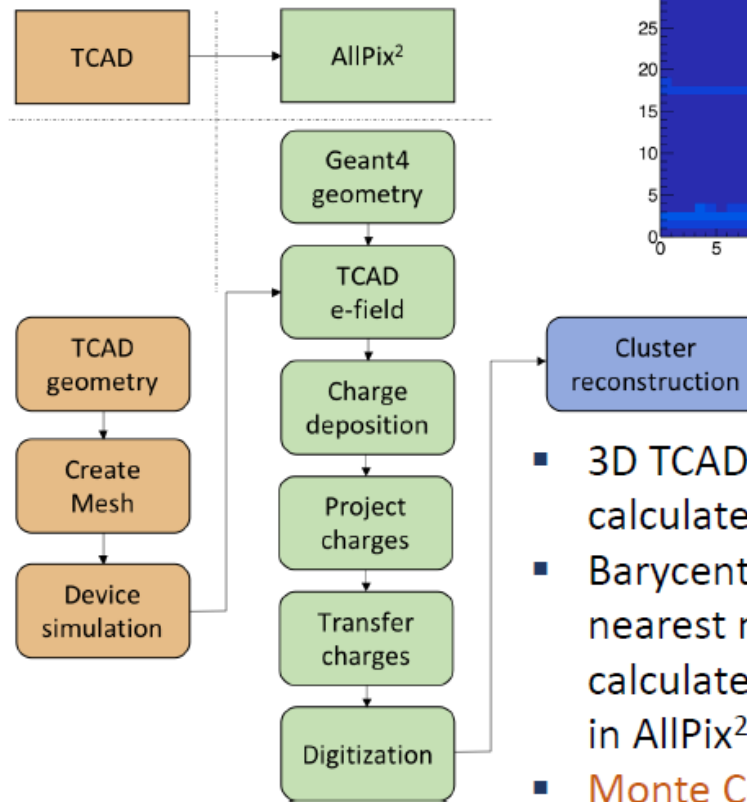
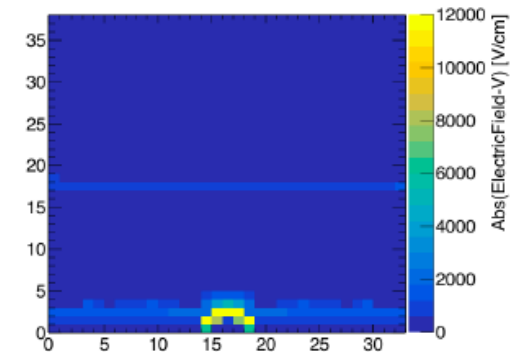
Build Sentaurus TCAD model



Extract electric field



Interpolate on regular mesh



- 3D TCAD simulations are used to calculate the Electric Field Map
- Barycentric interpolation using nearest neighbors is used to calculate results on regular mesh in AllPix²
- Monte Carlo sampling algorithm used for radioactive source

Simulation vs Measurement



- TCAD + AllPix2 combined simulation managed to re-produce most of the features observed in measurements

